



# 1. Introduction

# SCRIT electron scattering facility

M. Wakasugi et al., NIMB 317 (2013) 668. T. Ohnishi et al., NIMB 541 (2023) 380.



#### **Requirements for RI beams in SCRIT**

Low-energy ( $\sim$ keV) High quality (small emittance) High intensity ( $\sim$ 10<sup>8</sup> ions/pulse)





#### 1. Photofission of uranium

Photofission (Ex  $\sim$  15 MeV)

Thicker target can be applied.

#### 2. Low-energy and high intensity RI beam separator

1 kW e-beam + U 30g  $\rightarrow$  10<sup>11</sup> fissions/sec (<sup>132</sup>Sn 10<sup>9</sup>/sec)

First electron-beam ISOL facility in Japan First full-scale ISOL facility in RIKEN

3. Sharing of electron beam driver

Shared use with the injection to storage ring  $\rightarrow$  Cost effective

4. Independent RI beam separator



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# Photo fission vs Proton induced fission



Photofission has advantage to produce more neutron rich (2 $\sim$ 3 neutron) unstable nuclei.



#### 1. Photofission of uranium

Photofission (Ex  $\sim$  15 MeV)  $\rightarrow$ Thicker target can be applied. More neutron rich unstable nuclei than proton beam

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# 2. ERIS setup

#### Production target + Ion source + Transport line



- 2009 Construction start
- 2011 Commissioning & Uranium target production
- 2013 First RI beam produced by uranium photo-fission
- 2016 Grid operation for pre-stacking
- 2017 Surface ionization type ion source
- 2022 e-RI scattering experiment using online-produced RI



## Production target

### Self-made Uranium carbide disk

Uranyl nitrate solution mixed with graphite powder (20µm)

Oxidization around 500 °C 180 MPa compression with no binder

Φ 20 mm, t = 1 mm

#### Uranium-oxide disk

Carbothermal reduction  $U_3O_8 + C \rightarrow 3UO_2 + CO_2$  at 600-800°C <u> $UO_2 + 4C \rightarrow UC_2 + 2CO$ </u> at 1100-1600°C Ref. Gmelin handbook Supp. Vol. C12

#### Uranium carbide disk

Φ 18 mm, t 0.8 mm
43 disks U-28 g
→ U density 3.2 g/cm3)









Left side: Ta converter Right side: C spacer



### Ion source at ERIS



10





# 3. Results

#### **RI** production with FEBIAD



FEBIAD ion source U 15g 10W electron beam

Overall efficiency = Release×<u>Ionization×Transport</u> Exp./Calc. Target~Ionization from <sup>129</sup>Xe gas (14~15%)

	Rate at 10W (atoms/s)	Calc at 10W (atoms/s)	Overall	Release
<sup>138</sup> Xe	3.9×10 <sup>6</sup>	$7.1 \times 10^{7}$	5.5 %	40 %
<sup>132</sup> Sn	2.6×10 <sup>5</sup>	$1.3 \times 10^{7}$	2.0 %	14 %



# Two stage stacking inside ERIS & FRAC

**Conversion from DC to pulse beam** 





# <sup>137</sup>Cs beam production for e-RI scattering

ERIS 40 Hz, FRAC 1 Hz, RTM 15W, U 28g at FRAC exit



<sup>137</sup>Cs pulse beam: 2×10<sup>7</sup> ions/pulse to SCRIT(ERIS 40Hz, FRAC 0.25 Hz)

World's first electron scattering with online-produced RI





# Towards the supply of high intensity RI beams

## 1. Upgrading of e-beam driver

Improvement items for  $1\sim 2 \text{ kW}$  e-beam

High frequency ( $\sim 10 \text{ Hz} \rightarrow \sim 100 \text{ Hz}$ ) High peak current ( $\sim 0.5 \text{ mA} \rightarrow \sim 2.5 \text{ mA}$ ) Long pulse width ( $\sim 5 \text{ µs} \rightarrow \sim 10 \text{ µs}$ ) Upgrading of RTM has been already started. New klystron system New injection line...

# 2. Upgrading of ERIS

Improvement of overall efficiency Uranium carbide target → Nano material More efficient structure of ion source Improvement of RI separation



Isobar separation → limura-san's talk&Matsubara-san's poster

- 3. High-power e-beam operation
  - Shielding
  - Maintenance scenario
  - Target operation



# Shielding

-400

Additional

shield

Items for consideration in shielding

- Radiation level for outside of controlled area
- Prevent of radioactivation for electronics and devices



#### Phits calculation ( $\pm$ 5mm from beam plane)



# **Evaluation of radiation level**

## Enhancement of shielding

Ceiling shield for ion source Concreate: 2.4x2.4x0.6m<sup>3</sup> Pb block: 0.8x0.8x0.1m<sup>3</sup>



## Maintenance scenario

### Residual radiation from target

Measured data: 20 cm from target with 20W  ${\sim}50~\mu\text{Sv/h}$  after 2 weeks

➔ 2.5 mSv/h after 2 weeks @ 1kW

 $\rightarrow$  < 20 µSv/h after 2 years...

Calculation  $\rightarrow$  10 times larger Estimation of various locations

Waiting time for work: several weeks

## Remote handling system

Condition: 20 min. work, 2 mSv/h at 1m

Simpler system than other facilities

- Crane system
- Specialized working tools
- Preparation of storage space



#### Higher power(~100 kW) facility



ISAC target module at TRIUMF

G. Minor et al., Nuclear Engineering and Technology 53 (2021) 1378



## Target operation

Uranium carbide → Carbon nano material Fast release, Long lifetime A. Gottberg, NIMB 376 (2016) 8

Problem: Easily oxidization in the air



Uranium carbide with graphene  $\rightarrow$  Oxidization began within a minute of being released in the air.

Present: Small glove box (only target) → Large glove box (Ion source)











# Summary

- ERIS at the SCRIT electron scattering facility was constructed and the development has been continued.
- The world's first electron scattering with online-produced RI was successfully conducted.
- The upgrade for high intensity RI beam has been already started.

Electron scattering with <sup>132</sup>Sn will be performed soon.

For high power e-beam operation, global collaboration with other ISOL facilities is very important.



# SCRIT collaboration

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# Thank you for your attention!